

Fig.2

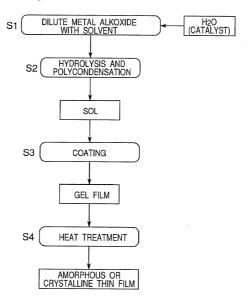


Fig.3

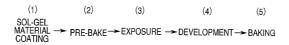


Fig.4 PRIOR ART

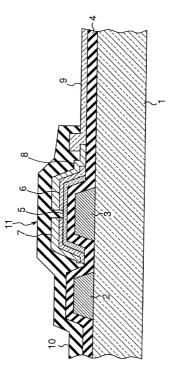


Fig.5 PRIOR ART

	1	675
PROCESS	6	CLEANING
ETCHING AND RESIST STRIPPING PROCESS	(8)	Y> FESST -> PRE-BAKE> EXPOSURE> DEVELOPMENT> POST-BAKE> ETCHING> STRIPPING STRIPPING> CLEANING
	(2)	
PHOTORESIST PATTERNING PROCESS	(9)	POST-BAKE
	(2)	-DEVELOPIMENT →
	(4)	▼ EXPOSURE →
	(3)	▼ PRE:BAKE
	(5)	¥ RESIST ↓ COATING
ITO FILM FORMING PROCESS	(F)	98